The Genki XP platform pushes industrialization of high energy and high power picosecond lasers further. The system is based on the ultra-stable Genki seed laser and provides clean pulses shorter than 10 ps, which is an optimal pulse duration window for many micromachining applications. To satisfy the increasing demand of picosecond laser workstations, the Genki XP has been optimized to provide up to 100 W of average power and 300 μJ pulse energy at the industry-standard wavelengths of 1030 and 1064 nm. The laser can be tailored to work at lower repetition rates with even higher energies or at several MHz to follow high-speed automated processes. The Genki XP has been designed for the easiest and most cost-effective possible system integration can be mounted in any direction and offers full remote control capability.

**OUTSTANDING FEATURES:**
- Pulse energy up to 300 μJ
- High pulse quality
- Narrow spectral width
- Excellent energy and pointing stability
- Mountable in any direction
- Maintenance free – no alignment required
- Complete remote control
- Burst mode
- 24/7 operation

**OPTIONS:**
- Green 522 nm
- UVA 355 nm
- UVC 266 nm
- Synchronization to external clock

**MAIN APPLICATIONS:**
- Material processing
- Glass and sapphire cutting
- Plasma generation
- Nonlinear optics
Pulse Profile

Autocorrelation Signal

- Measured
- Ideal 8 ps Gaussian

41 MHz
100 W

Average Power (W)

Pulse Energy (μJ)

Beam Profile

Application

P2 scribe on Mo/CIGS/IZO thin film solar module realized with the Genki XP, 4W, 10 kHz, 1064 nm.

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